

wherein said temperature control means is a resistance heating element equipped on the surface of said ceramic substrate or inside of said ceramic substrate.

3. (New) The ceramic heater according to claim 1,

wherein said temperature control means is a Peltier device equipped on the surface of said ceramic substrate.

4. (New) The ceramic heater according to claim 1,

wherein an electrostatic electrode is embedded in said ceramic substrate.

5. (New) The ceramic heater according to claim 1,

wherein a chuck top conductor layer is formed on the surface of said ceramic substrate.

6. (New) The ceramic heater according to claim 1,

wherein said ceramic substrate is an oxide ceramic.

7. (New) The ceramic heater according to claim 1,

wherein said ceramic substrate is a non-oxide ceramic containing oxygen.

8. (New) The ceramic heater according to claim 1,

wherein said ceramic substrate is a non-oxide ceramic containing 0.05 to 10% by weigh of oxygen.

9. (New) The ceramic heater according to claim 1,

wherein said ceramic substrate contains carbon.

10. (New) The ceramic heater according to claim 1, wherein said ceramic substrate comprises aluminum nitride.

11. (New) The ceramic heater according to claim 1, wherein said ceramic substrate has 1×10^8 or more pores which have a diameter of $0.5 \mu\text{m}$ or more per m^2 by surface measurement with a microscope.